## **CLAIM AMENDMENTS**

In this Response, Claims 1, 3, 4, 7, 8, and 9 have been amended.

1. (currently amended) An apparatus to support a stent during the process of applying a coating substance to a stent:

a support fixture to support a stent during the application of a coating substance;

a <u>pressure</u>processing system to modify the coating substance applied to the stent supported by the support fixture; and

a coupling element configured to connect one side of the support fixture to the <a href="mailto:pressure-processing">pressure-processing</a> system to allow the support fixture to be rotated with respect to the <a href="pressure-processing">pressure-processing</a> system.

- 2. (original) The apparatus of Claim 1, wherein another side of the support fixture is capable of being connected to a motor for rotating the support fixture.
- 3. (currently amended) The apparatus of Claim 1, wherein the <u>pressure-process</u>-system is a vacuum device<del>pressure system to apply a vacuum pressure to the support fixture.</del>
- 4. (currently amended) The apparatus of Claim 1, additionally including a conduit connecting the coupling element to the <u>pressureprocessing</u> system.
- 5. (original) The apparatus of Claim 1, wherein the support fixture includes a component extending into a bore of the stent, wherein the component has an outer surface in contact with an inner surface of the stent.
- 6. (original) The apparatus of Claim 1, wherein the support fixture includes a component extending into a bore of the stent, wherein the component has an outer surface that does not make contact with an inner surface of the stent.

7. (currently amended) An apparatus to support a stent during the process of applying a coating substance to a stent:

a coupler;

a support fixture, connected to one side of the coupler, to support a stent during the application of a coating substance to the stent; and

a conduit, in fluid communication with the support fixture, connected to another side of the coupler, wherein the coupler allows the support fixture to be rotated with respect to without the conduit being rotated.

- 8. (currently amended) The apparatus of Claim 7, wherein the conduit is configured to be connected to a <u>pressureprocessing</u> system.
- 9. (currently amended) The apparatus of Claim 8, wherein the <u>pressure processing</u> system is a <u>vacuum device pressure system</u>.